







<u>IN THE UNITED STATES PATENT AND TRADEMARK OFFICE</u>

Applicants:

SCHULTZ ET AL.

Serial No:

09/627,559

For:

ILLUMINATION SYSTEM WITH A PLURALITY OF LIGHT

SOURCES

Filed:

JULY 27, 2000

Examiner:

BERNARD E. SOUW

Art Unit:

2881

Docket No.: 637.0003USU

AMENDMENT

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Applicants are submitting the present document in response to an Office Action dated June 27, 2002. Please amend the above-noted application as follows:

IN THE SPECIFICATION

Please amend the portions of the Specification identified below to read as indicated herein. A version of the amended portions of the Specification with markings to show changes made is included at the end of this document.

Page 3, paragraph starting at line 26

If the numerical aperture in the plane of the wafer is in the range $NA_{wafer} = 0.1 - 0.25 \frac{N}{C}$ then in the case of 4:1 systems, a numerical aperture in the reticle plane of $NA_{reticle} = 0.025$ -

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